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# SECOND QUARTERLY REPORT PRESSURE MEASURING SYSTEMS FOR CLOSED CYCLE LIQUID METAL FACILITIES

Edited by  
Richard E. Engdahl

PREPARED FOR  
NATIONAL AERONAUTICS AND SPACE ADMINISTRATION  
CONTRACT NAS 3-4170  
September 28, 1964

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**CONSOLIDATED CONTROLS CORP.**  
**BETHEL, CONNECTICUT**



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SECOND QUARTERLY REPORT  
June 1--August 31, 1964

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FOR  
CLOSED CYCLE LIQUID METAL FACILITIES

Edited by  
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Bethel, Connecticut

# **FOREWORD**

The major contributors to this development program are Mr. R. Engdahl, Project Manager, Mr. Anthony Cassano, Mr. David Mends, Mr. Charles Schoenfeld and Mr. William Waller.

# 33376

## ABSTRACT

Continuing development of a series of pressure transducers for liquid metal systems is described. Problems encountered in fabricating the pressure capsule are outlined along with the anticipated solutions. The experimental program for completing the evaluation of the thermionic and variable impedance detector systems is described. Some details of the test facility are discussed. These include the liquid potassium test capsules and the method of measuring diaphragm deflection.

*Author*

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## 1.0 Introduction

The objective of Contract NAS 3-4170 is to develop a series of pressure transducer equipment compatible with advanced closed cycle power systems. These systems utilize liquid metals such as mercury, sodium, potassium and other alkali metals as working and heat transfer media at elevated temperatures. Pressure measurements in the high temperature liquid, vapor, and two phase streams will be required for research, design and control purposes for SNAP-8 and other liquid metal space power systems. Since small pressure changes might indicate the onset of instability, instruments are required that can follow and record minute changes. In addition, space flight requires light-weight pressure measuring systems capable of enduring long periods of unattended operation.

Eight pressure ranges are included in this work covering both absolute and differential pressure instruments. The absolute ranges are 0-5,

0-20, 0-80, 0-300, and 0-500 psia. The differential pressure ranges include  $\pm 1$ ,  $\pm 5$ , and  $\pm 20$  psid at static pressures to 300 psia. All systems are to include overload protection to 100 percent of range.

Liquid metal pressure measurements at elevated temperatures pose many problems which challenge the designer and demand the best from available materials. To establish a firm design base for the complete series of transducers, four materials and two transducer systems will be evaluated.

These design data will then be incorporated into a series of transducers covering the eight instrument ranges defined above. The selected material and signal transduction system will be developed for use as either ground or flight hardware.

## 2.0 Summary

Progress in the design and fabrication of the FS-85, C129Y, W-25Re and T-222 pressure capsules is presented. Using the simplified capsule design with spark discharge machined discs, FS-85 and C129Y alloy capsules have been assembled and sectioned to determine the weld soundness and depth of weld penetration. Work on the W-25Re alloy capsule has involved similar weld sample tests and the development of a transition piece between the capsule and the columbium pressurization system. Work on the T-222 alloy capsule is awaiting delivery of this material.

The experimental thermionic transducer has been designed, built, and is now undergoing initial check out. The only apparent problem has been a heater failure during the initial vacuum chamber bake-out. Steps are being taken to correct the deficiency.

The analysis of the variable impedance sensor resulted in expressions requiring computer

solutions. An alternative experimental program has been developed which will obtain the data needed to proceed with the evaluation of the variable impedance device. In addition, the experiments will provide data on the skin depth phenomena which, at present, must be assumed in the analytic treatment. A pancake coil-diaphragm mock-up has been fabricated and initial experiments have been conducted. Resonance effects introduced by instrument impedances made these tests inconclusive. Further tests, using a Q-meter instrument, have corrected this situation.

Five electrical terminals have been built and tested at 1800°F and up to 300 psia internal pressure. The results are presented along with a review of additional testing performed in the very high vacuum test facility ( $10^{-8}$  Torr).

The multiple station test facility is basically complete. The system has been cleaned and baked out in preparation for the insertion of

the test capsules. The only remaining work is the mounting of the camera and the final piping of the argon pressurization system.

### 3.0

#### Design and Fabrication of Pressure Element

Work is progressing on the FS-85, Cl29Y and W-25Re alloy capsules. The T-222 alloy material is not yet delivered. The necessary electron-beam welding techniques are being developed along with efforts to supplement available welding facilities.

Diaphragm capsules were assembled from FS-85 and Cl29Y alloys, photographs of which are shown in Figure 1, but when these capsules were sectioned to determine the depth of weld penetration it was found that insufficient penetration had been obtained. A section of the FS-85 capsule is shown in Figure 2.

Work on these capsules has been delayed by scheduling problems in the electron-beam welding facilities. Alternate sources are being investigated in order to speed up the program.

A number of attempts have been made to electron-beam weld FS-85 columbium alloy tubing (pressurization system) to the W-25Re alloy (pressure capsule),

but in every case the weld showed cracking. It is felt that the cracking in the weld was probably caused by diffusion of Cb, Ta, etc. into the W-25Re alloy, decreasing the solid solubility of Re in W so that some  $\sigma$  phase was formed. The W-Re equilibrium diagram (Reference 1) is shown in Figure 3, where it is seen that the W-25Re alloy lies very close to the  $\beta/\beta + \sigma$  phase boundary which is at 26 percent Re at 1500°C.

The next approach was to employ a weld insert of a dissimilar metal between the W-25Re and the FS-85 alloy in an attempt to overcome the weld cracking. Inserts of Cb-1Zr, molybdenum, rhenium, Mo-50Re were fabricated and mock-ups were made by electron beam welding as shown in Figure 4. Metallographic sections of the welds are shown in Figure 5. It is seen that in every case the welds were cracked, the only exception being the W-25Re to the Mo-50Re insert.

A possible explanation for the success of the W-25Re to Mo-50Re welds may be found in the



ternary equilibrium diagram for W-Mo-Re (Reference 2) shown in Figure 6. It will be seen that any conceivable alloy combination of W, Mo and Re which might result from melting together W-25Re and Mo-50Re must fall within the alpha single phase area (corresponding to the  $\beta$  phase area in the W-Re binary diagram, Figure 3) bounded by the points Mo-W-Y-Z in Figure 6, and will lie to the left of the  $\alpha/\alpha + \sigma$  phase boundary, YZ. Therefore, no  $\sigma$  phase should occur in the weld.

The Mo-50Re insert was cracked where it was welded to the FS-85. This suggested the possibility of using a Mo-50Re tube for making the connection between the pressurization system and the capsule. Another insert of Mo-50Re was successfully welded to W-25Re. Accordingly, several pieces of Mo-50Re tubing were obtained, and an attempt is being made to assemble a W-25Re capsule in this manner.

Another technique considered was to make the tube from W-3Re alloy which might prove weldable

to W-25Re. This material is available in rod form. The intention was to make the rod into a tube by spark discharge machining.

A sample of W-3Re rod (0.250 inch diameter) was ordered, and was found to be broken into several fragments as a result of damage during shipping. Subsequent discussion with the vendor revealed that the ductile/brittle transformation temperature of this alloy is about 150°C in a rod of this diameter, and that this transformation is below room temperature only in heavily worked wire. This material was obviously unsuitable for use in the pressure transducer.

The simplified form of diaphragm capsule is presently being assembled as shown in Figure 7B. In this design the diaphragms are machined from thicker material, and it will be seen that the simplified design comprises a tube and four discs with only four welds. The original design shown in Figure 7A comprised a tube plus eleven parts

and required eleven welds. It is proposed to assemble any future W-25Re capsules according to the simplified design, the discs being spark discharge machined.

#### 4.0      Deflection - Electrical Signal

The analysis of the thermionic and variable impedance detector systems has been completed and is fully presented in the First Quarterly Report (Reference 3). Emphasis has now shifted to an experimental approach to confirm the anticipated performance of the thermionic diode and to obtain data needed to proceed with the evaluation of the variable impedance device.

#### 4.1 Thermionic Diode Sensor

A dual emitter thermionic test device has been designed. Figure 8 presents an assembly view of the dual diode and Figure 9 shows the device installed in one of the test facility vacuum chambers. The emitters are Philips Type B tungsten dispenser cathodes (0.120 inch diameter, 0.040 inch thick) with standard barium oxide and aluminum oxide impregnation. The reference collector is mechanically fixed 0.006 inch from its emitter. The active collector-emitter distance is adjustable between 0.004 and 0.006 inch by means of the micrometer assembly mounted on the top vacuum flange. Electrical connections for the diode heater power as well as the emitters and collectors are made using feed-through terminals installed in this flange. Nickel rods (0.1 inch diameter) extend from the feed-through terminals down into the test chamber to the diode where connections are made to the various device elements.

A tungsten wire (0.012 inch diameter) formed to fit the cavity between the two emitters serves as the heater. The cavity and the heater are individually plasma sprayed with aluminum oxide to electrically insulate the heater from the emitters. Tests have established the ability of the heater to raise the emitter assembly to the desired operating temperature of 2100°F (1420°K).

#### 4.1.1 Test Circuitry and Instrumentation

The thermionic diode system described in the First Quarterly Report may be simulated by the test circuitry shown in Figure 10.

The object of the experiment is to determine the linearity achieved between active collector distance and the difference current ( $i_a - i_r$ ) when the sum-of-the-currents ( $i_a + i_r$ ) is held constant by adjusting the voltage  $V$ . Calculations have indicated that this linearity is about 3 percent when ( $i_a + i_r$ ) is maintained at a value of 144 milliamperes. This corresponds to an active collector distance of 0.006 inch, a voltage  $V$  of 20 volts and an emitter temperature of 1420°K. The possibility of improving the linearity by having ( $i_a + i_r$ ) vary with active collector position will also be investigated. Although the difference current amplifier and the feedback regulated power supply mentioned in the First Quarterly Report will not be used in this system, all the current and voltage values will be measured and correlated

with the analysis. These data should then provide the information needed to formulate the signal conditioning equipment requirements.

An equally important phase of the program will involve the determination of errors introduced by changes in operating parameters. The parameters of interest are emitter temperature (monitored by pyrometry through the test chamber viewing window and adjusted by changing the heater input level) and the voltage  $V$  applied to the collectors (monitored by a voltmeter and potentiometer adjusted). Analysis has indicated that errors introduced by reasonable changes in these parameters will be minimal. Experimental verification would be valuable and of considerable importance in selecting the preferred detector system.



#### 4.1.2 Preliminary Test Results

The first test assembly failed following the initial bakeout in the vacuum chamber. This bakeout is at 1800°F where the temperature is raised to this value in stages with the restriction that the pressure in the test chamber shall not exceed  $10^{-6}$  Torr. This precaution is necessary to avoid emitter poisoning and the resultant loss of emission capability. Preliminary checks indicated an open circuit heater. Post mortem examination revealed that the spot weld joints between the tungsten heater leads and the nickel feed-through rods had opened. In addition, the tungsten wire broke inside the emitter assembly and made effective repair of the device impossible. It is felt that excessive embrittlement of the tungsten wire due to the bakeout was at fault.

The second test assembly, presently in progress, will incorporate modifications to solve the problems mentioned above. The tungsten heater will be replaced by a heater which is more ductile and less

liable to embrittlement upon heating. In addition, the heater leads will have ceramic tubing to protect them inside the emitter sandwich. This tubing will terminate outside the sandwich assembly. Also, a flexible transition connection will be used between the heater wire and the nickel rod to absorb any mechanical strain generated during the cool-down period.

## 4.2

Impedance Bridge Sensor

In order to evaluate the analytical approach presented in Appendix C of the First Quarterly Report, an attempt has been made to determine, by slide rule calculations, the inductance of a single turn pancake coil in the presence of a conducting diaphragm. The details of this effort are found in Appendix B. The conclusion obtained was that the analytical approach would not yield results unless a computer is utilized.

Two alternatives present themselves. One would be to use the computer and the other to use an experimental program to complete the analysis. The experimental program is preferred since it would complete the design data needed and also shows promise of providing the skin depth values which must be assumed in the computer program.

#### 4.2.1 Experimental Program

The main objective of the experimental program will be the determination of pancake coil inductance as a function of diaphragm position. In addition, it is expected that the program will result in data that will verify the basic premise of the analysis; the presence of an image coil whose position is determined by a skin-depth phenomena. The discussion that follows expands upon this last statement.

Image theory has been proposed as a valid method of determining the coil inductance. Of prime importance is the distance between the pancake coil and the image coil. This distance is in turn determined by a skin depth phenomena experienced in the diaphragm. At some effective skin depth (which may be postulated to be some multiple of a unit skin depth) inside the diaphragm, the induction field of the pancake coil will tend to zero and the pancake and image coils become equidistant from this plane. This phenomena is

dependent upon the resistivity of the diaphragm material. As an example, consider a perfectly conducting diaphragm (resistivity = 0). The field does not enter the diaphragm at all and has its zero value at the diaphragm surface. For this case the pancake coil to image coil distance will be twice the pancake coil to diaphragm distance. In addition, the pancake coil inductance will vary between a value of zero when the distance is zero and a finite value, e.g.  $L_{\infty}$ , corresponding to complete absence of a diaphragm. The inductance  $L$  will tend to this value as the spacing increases. Although the exact shape of the curve is uncertain, Figure 11 indicates the general trend. The fact that  $L = 0$  at  $d_c = 0$  for  $\rho_{r1} = 0$  means that the pancake and image coils are so close to each other that their axial fields cancel out in the plane of the pancake coil.

Now, an important point must be made. The pancake coil inductance is determined by the opposing interaction of two axial induction fields; one due

to the pancake coil itself and the other due to the image coil. The strength of the image field is governed by the distance between the coils. This distance is determined by two parameters; the diaphragm spacing and the effective skin depth as established by the diaphragm resistivity. However, the sum of diaphragm spacing and effective skin depth is the important thing. In other words, two diaphragms of different resistivities will result in the same pancake coil inductance if the diaphragm spacing is adjusted to compensate for the difference in effective skin depth. As resistivity increases, skin depth increases. Referring to Figure 11, the inductance  $L_2$  for a spacing  $d_{c2}$  with a zero resistivity diaphragm would correspond to the same inductance  $L_2$  caused by a diaphragm with zero spacing and an effective skin depth of  $1/2 d_{c2}$  determined by a finite resistivity  $\rho_{r2}$ . This statement applies also to inductance  $L_3$  where a diaphragm with zero spacing would have an effective skin depth of  $1/2 d_{c3}$  determined by resistivity

$\rho_{r3}$ . If a diaphragm of very low resistivity (e.g. copper) is used, the  $\rho_{r1} = 0$  curve will be approached. Using this curve, an effort may be made to determine correlations between effective skin depth and resistivity. Using the standard formula for unit skin depth as a function of resistivity, an effort will be made to determine whether the effective skin depth postulated above is a constant multiple of the unit skin depth.

The use of diaphragms of various resistivities should result in a series of parallel curves intersecting the ordinate at larger values of inductance for larger values of resistivities. This procedure will give an estimate of inductance change with diaphragm temperature. A temperature change will result in a resistivity change affecting skin depth and inductance even at constant spacing.

#### 4.2.2 Preliminary Test Results

A 20 turn single-layer pancake coil (I.D. = 3/16 inch, O.D. = 9/16 inch, AWG 32 heavy Formvar insulated magnet wire) has been fabricated and encapsulated in the surface of a block of lucite. Diaphragm mock-ups of various materials covering a range of resistivity values and thicknesses (copper,  $1.7 \times 10^{-6}$  ohm-cm, 0.015 inch; cupro-nickel,  $39 \times 10^{-6}$  ohm-cm, 0.031 inch; monel,  $49 \times 10^{-6}$  ohm-cm, 0.015 inch; K-monel,  $58 \times 10^{-6}$  ohm-cm, 0.021 inch) have been prepared and mounted on polystyrene rods. A test fixture has been constructed to allow mounting of the diaphragm samples in a support slide and positioning of the samples at various distances from the coil by means of a vernier micrometer. Figure 12 shows the test fixture.

Initial testing of the coil on the basis of impedance measurements proved inconsistent. This testing involved the use of a radio frequency signal generator and a calibrated oscilloscope



to obtain current and voltage parameters. Parallel resonance phenomena introduced by the impedance characteristics of the instruments made this method inconclusive.

The test coil must be considered as a parallel LC circuit element. This requires that two unknowns,  $L$  and  $C$ , be evaluated. While it may be assumed that the capacitance  $C$  is relatively constant, the inductance  $L$  is certainly a function of diaphragm spacing and, according to the proposed analytical model, a function of circuit frequency. For this reason, an independent determination of  $C$  will be used to fix one of the unknowns and the other unknown,  $L$ , can then be obtained from either resonance or impedance data.

Preliminary tests, using a Q-meter instrument, have eliminated the resonance problem mentioned above. Capacitance and inductance values for the coil parameters will be obtained from this system.

## 5.0 Electrical Terminal

Five terminals have been built and tested at 1800°F and up to 300 psia internal pressure. This testing was performed to establish the joint strength and thus supply design data for the final test terminal. The strongest unit lasted 4 hours at the maximum condition. It was noted that there was an oxide problem that apparently lowered the joint strength. Therefore, it was decided to terminate the series of tests until brazing and testing could be conducted in the  $10^{-8}$  Torr test environment. (See Section 6.0.) Table 1 presents the test results.

TABLE 1  
ELECTRICAL TERMINAL TEST RESULTS

<u>Unit No.</u>	<u>Max. Press.(psia)</u>	<u>Time @ Temp.</u>	<u>Location of Failure</u>
14	300	4 hrs.-1800°F	Break in ceramic joint
15	150	5 min.-1400°F	Tubulation failed
16	300	20 min.-1800°F	Break in ceramic joint
17	300	17 min.-1800°F	Break in ceramic joint
18	---	-----	Not leak tight when first brazed

It should be noted that the test pressure was applied from the inside of the terminal, and therefore, the stress in the joint was much more than if the pressure had been applied externally.

Additional terminal tests were performed in August in the Vacuum Test Facility. Oxide formation appeared to be eliminated but no improvement in joint strength was observed. Means for raising the remelt temperature of the braze are being investigated as a solution to this problem. Also a terminal design which would reduce the joint stress is being evaluated.

A group of terminals have been ordered for inclusion in this test program. Figure 13 illustrates this design.

## 6.0 Vacuum Test Facility

The basic design concepts of the multiple station test facility are contained in the First Quarterly Report. During this report period, substantial progress has been made in the construction of the facility, which is now basically complete. The system has been cleaned and baked out in preparation for the insertion of the test capsules. The only remaining work is the mounting of the camera and the final piping of the argon pressurization system. A photograph of the facility is given in Figure 14. Preliminary tests have resulted in manifold vacuum measurements of  $2 \times 10^{-9}$  Torr at room temperature and  $2 \times 10^{-8}$  Torr with one vacuum chamber heated to 1800°F.

### 6.1.1 Facility Design - Liquid Metal Capsule

A procedure has been formulated for filling the compatibility test capsules with potassium. Consolidated Controls Corporation will fabricate the capsules and supply them to a qualified outside organization which will perform the following tasks:

1. Charge the capsules with potassium under vacuum, and seal the capsules by electron-beam welding. Supply an analysis of the potassium used. Return the capsules to CCC for testing.
2. After testing at CCC, open the capsules, completely remove the potassium contained and analyze the potassium for impurities. Return the capsules along with the impurity reports to CCC.

### 6.1.2 Facility Design - Diaphragm Deflection Measurement

A major problem has been to find a technique for measuring the motion of the diaphragm to an accuracy of 1 percent of the total travel. A total travel of 0.002 inch requires the motion to be measured to an accuracy of 20 microinches.

Initial tests to determine the distance between two scribed lines revealed that the above accuracy ( $\pm 20$  microinches) could not be obtained by direct observation. Parallax errors, caused by movement of the observer's eye, together with the difficulty of positively identifying one particular pair of lines, dictated the use of a photographic technique to produce a photograph from which measurements could be taken.

In the photographic system, there are two sources of error, the optical system and the film itself. The optical system may be analyzed by considering the fineness of detail, or resolution, of the objective lens. This analysis, as it

applies to the present experimental set-up using a binocular microscope with a 4 inch working distance, is contained in Appendix C. A reasonable estimate of the maximum attainable resolution of this system is 360 microinches. However, this is an optical system error dependent upon parameters such as objective illumination, working distance, lens diameter, etc. Assuming that these parameters are held fairly constant, the error will also be constant over a number of photographs.

Of more immediate concern is the error introduced by the film itself (film dimensional stability, intrinsic resolution capability of the film, and emulsion response to both the light input and the development procedures). These effects will appear as reproducibility errors between photographs taken of identical objects under identical conditions.

The binocular microscope is equipped with a direct illuminator which reduces the working distance from 4 inches to 3 inches. Since the

test piece will be approximately 3.5 inches from the viewing window, the working distance of the camera system must be greater than this distance. The illuminator was therefore modified so that the working distance was increased to 3.75 inches.

A number of photographs were taken of a pair of scribed lines at nominal 30X and 40X magnification using the binocular microscope and a camera filled with Polaroid film. The distances between the images of the lines on the photographs thus produced were measured at 7X magnification by means of the binocular microscope fitted with a filar eyepiece. Differences of several hundred microinches were observed between successive identical photographs.

To overcome this difficulty, glass metallographic plates were used. Preliminary tests using the glass plates indicate that the individual plate can be read to an accuracy of 7-15 microinches. However, as in the case of the Polaroid film, differences were observed in measurements taken



between the same lines on different photographs. This reproducibility error, while not as severe as with the Polaroid film, was about 200 microinches. Present work is aimed at refinement of this latter technique and evaluation of the reproducibility error.

Several preliminary tests have been made using a mechanical system to amplify the diaphragm movement by a factor of about 10. Using this system, the reproducibility error of 200 microinches will be reduced to 20 microinches, assuming no other uncertainties. Figure 15 shows the system installed in a vacuum test chamber. Both the preliminary test mock-up and a pressure capsule installation are shown.

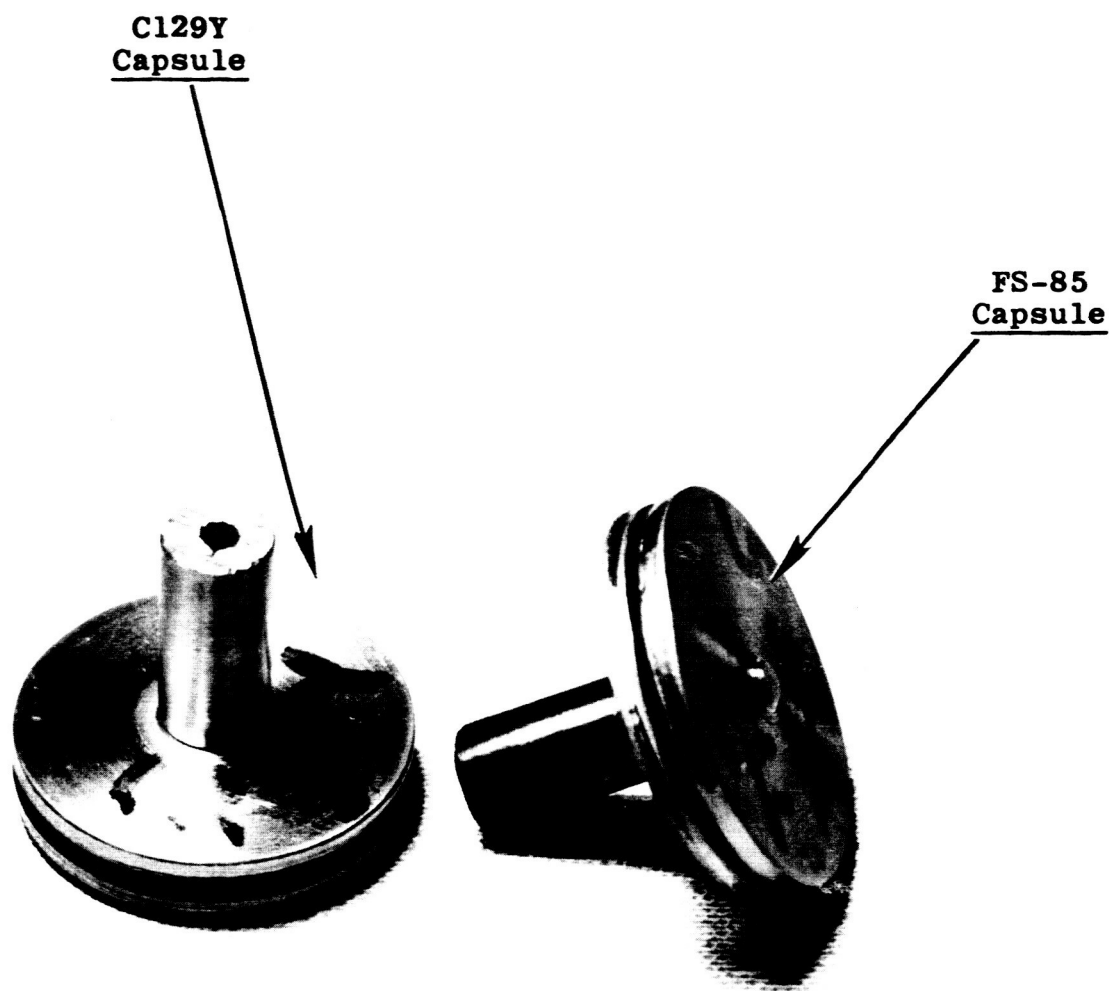
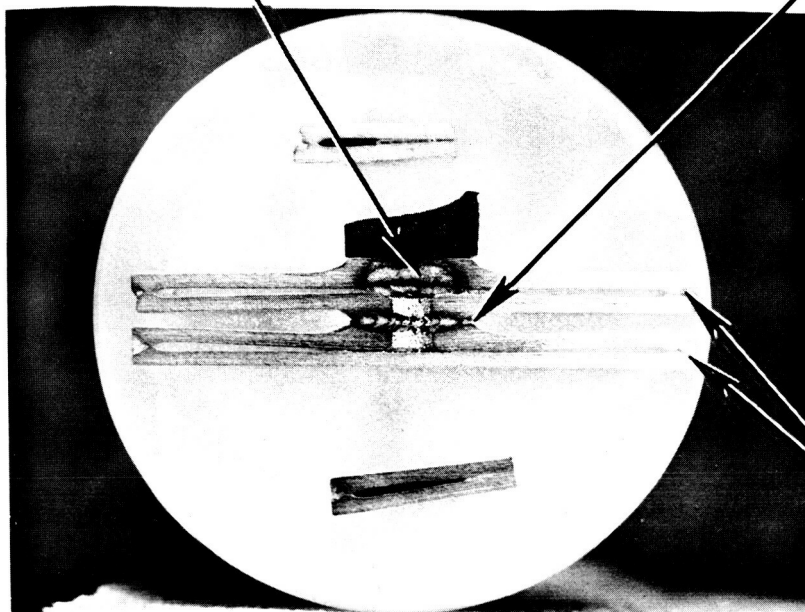


Figure 1  
FS-85, C129Y Diaphragm Capsules

Upper convolution-tube weld  
(Complete)

Convolution weld  
(Complete)



Peripheral Weld  
(Incomplete)

Section cut parallel to capsule diameter.  
Slight distortion occurred during mounting.

**Figure 2**  
**Weld Section of FS-85 Capsule**

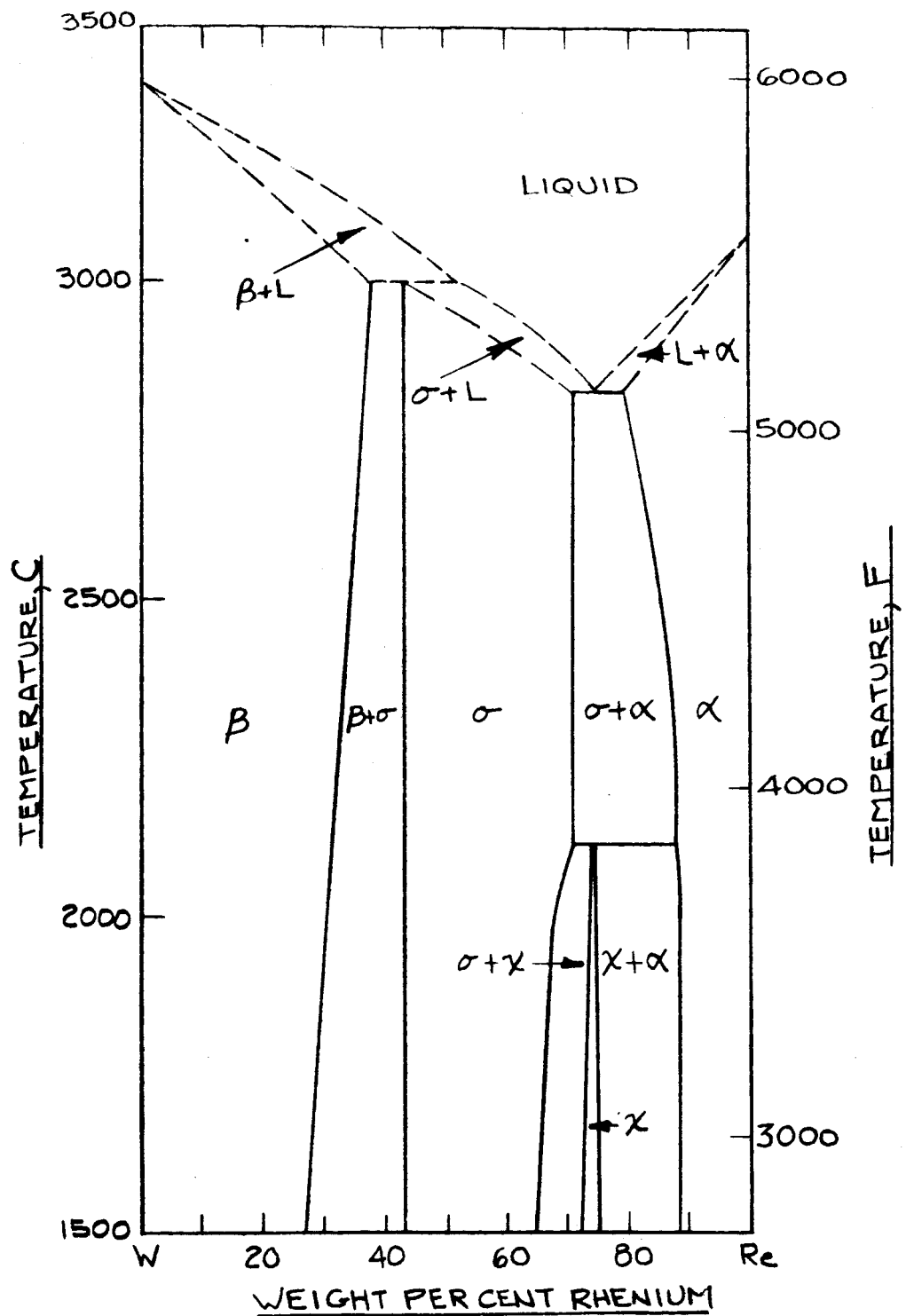


Figure 3  
W-Re Binary Equilibrium Diagram

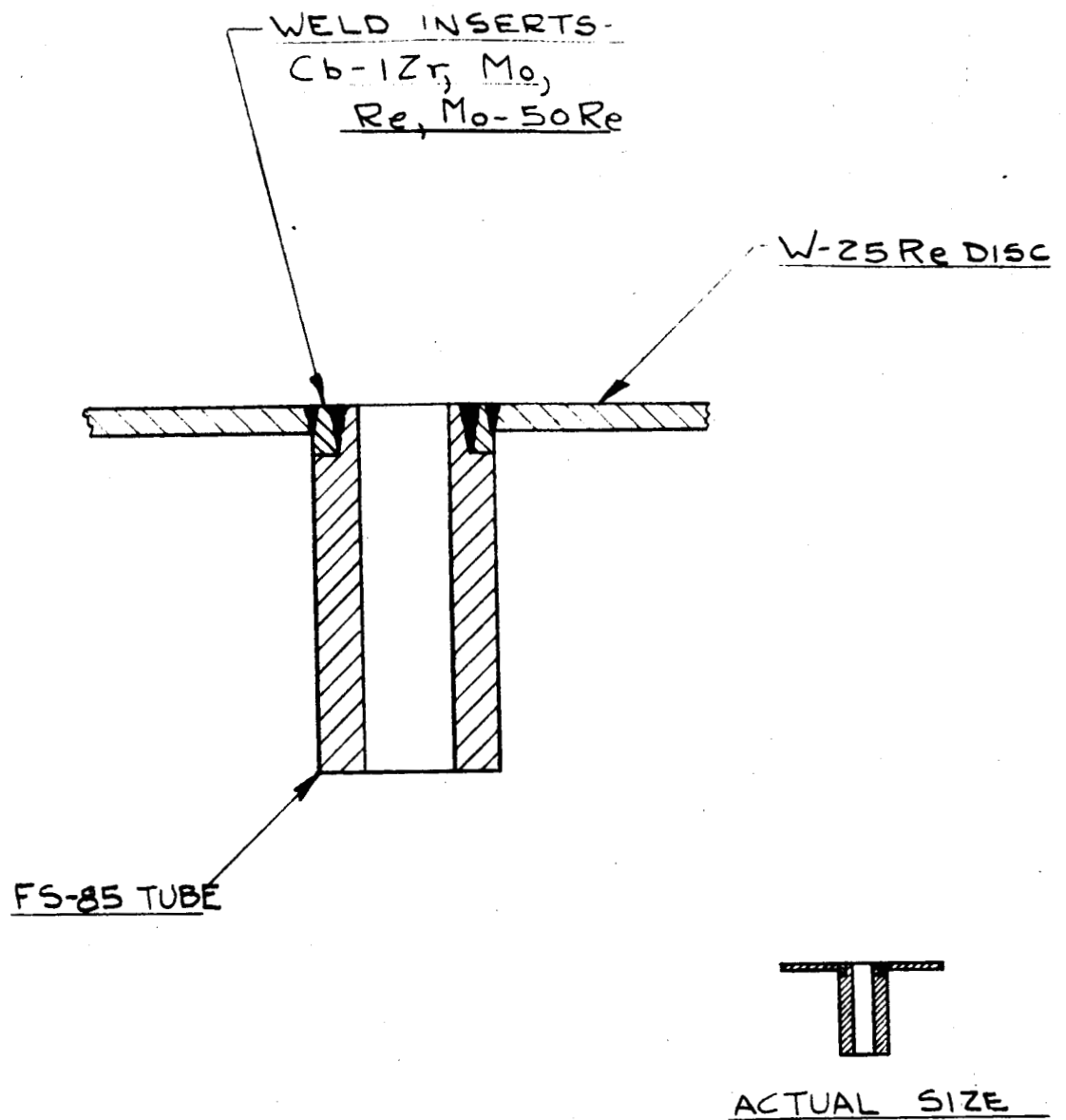
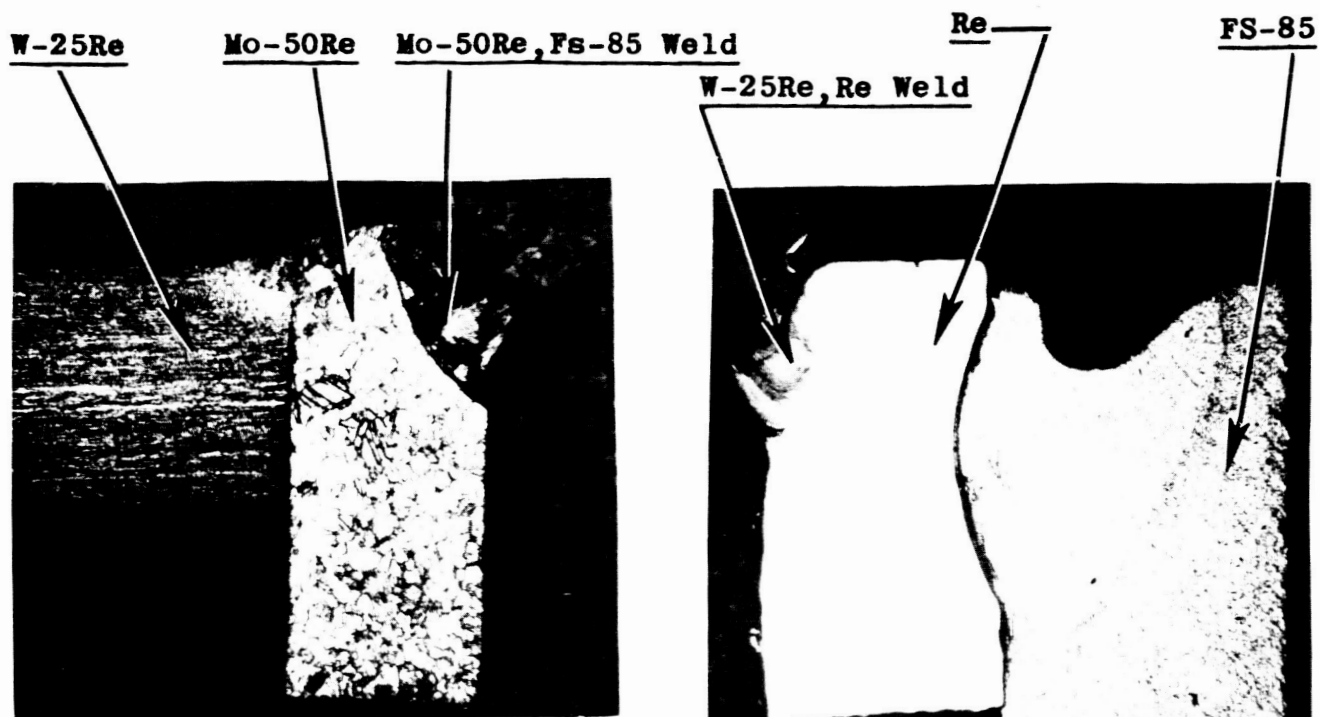
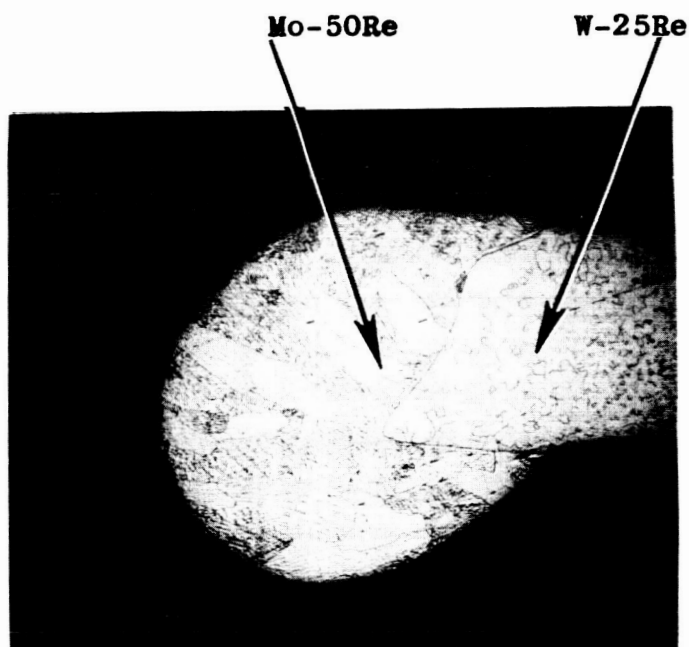


Figure 4  
E-B Weld Mock-ups Using Various Inserts



W-25Re, Mo-50Re weld incomplete.  
Mo-50Re, FS-85 weld broke off  
but intermetallic compounds and  
shattered weld are evident.

W-25Re, Re weld cracked and broke  
during sectioning. Re, FS-85  
weld complete.



Complete Weld

Figure 5  
Metallographic Sections of Welds

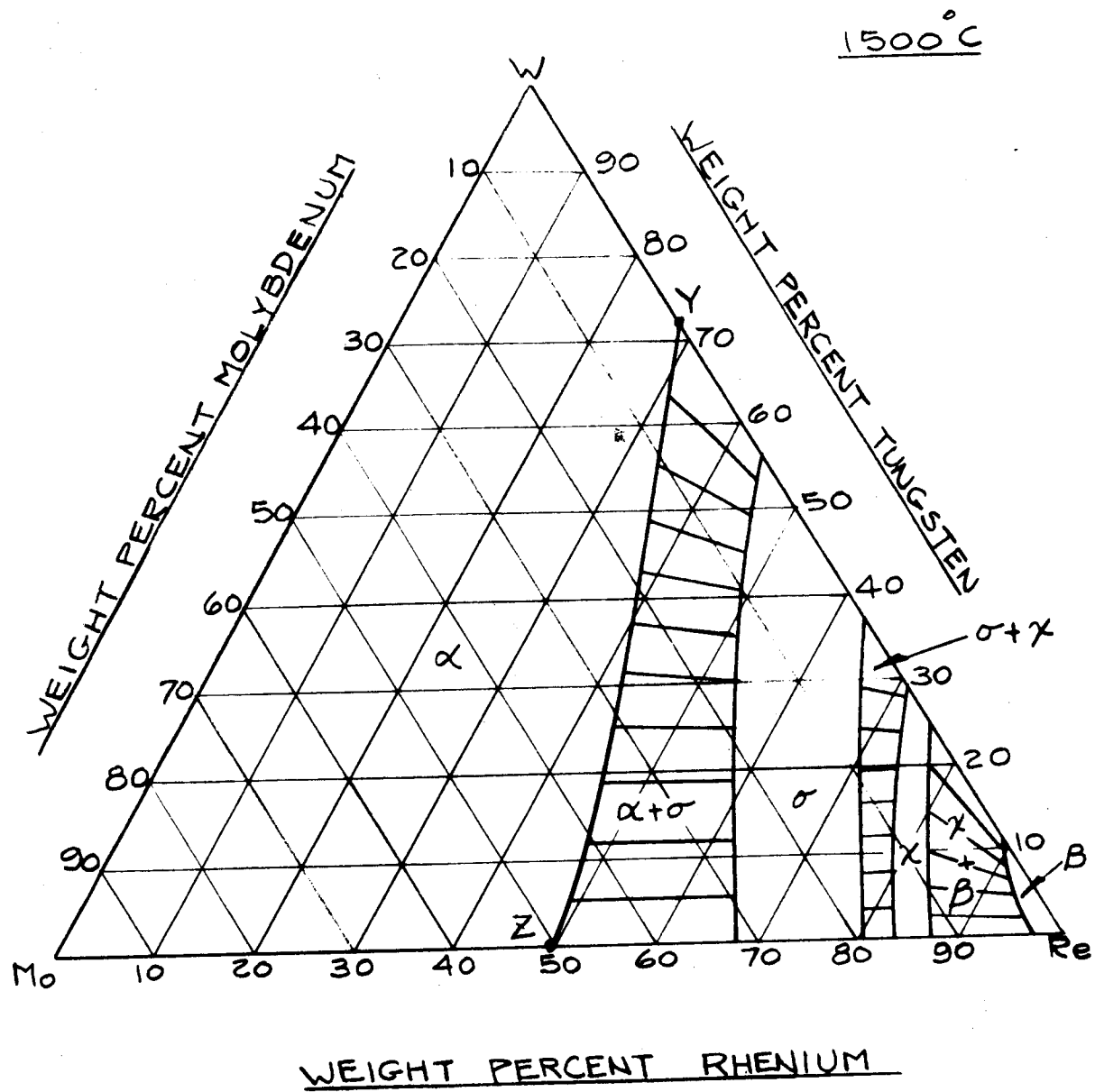
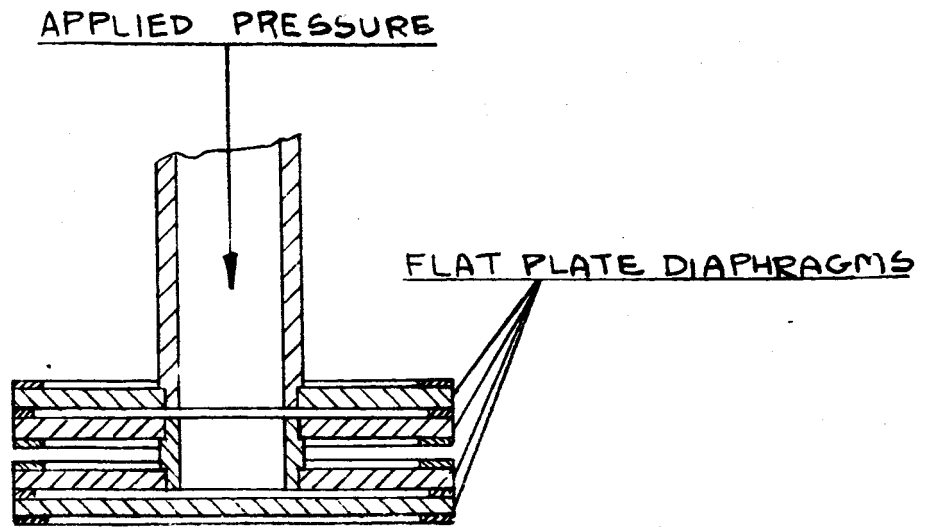
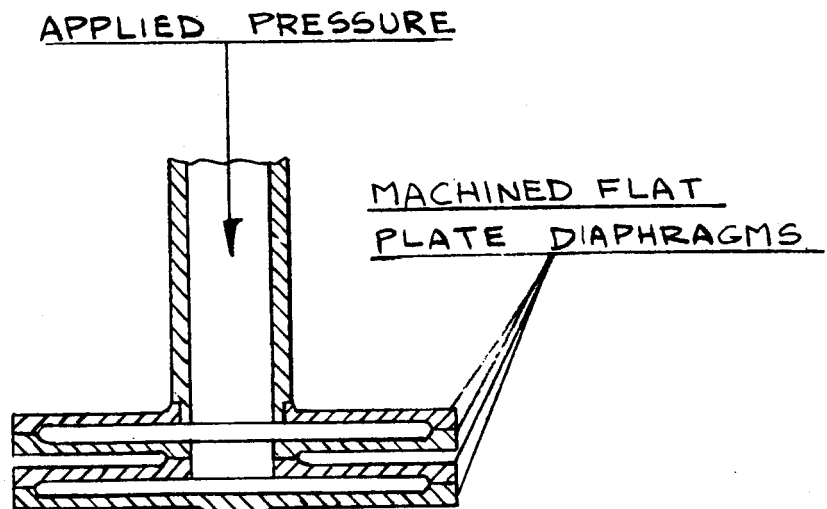


Figure 6  
W-Mo-Re Ternary Equilibrium Diagram



**Figure 7A**  
**Ring Plate Diaphragm Design**



**Figure 7B**  
**Machined Diaphragm Design**

**Figure 7**  
**Diaphragm Capsule Design**



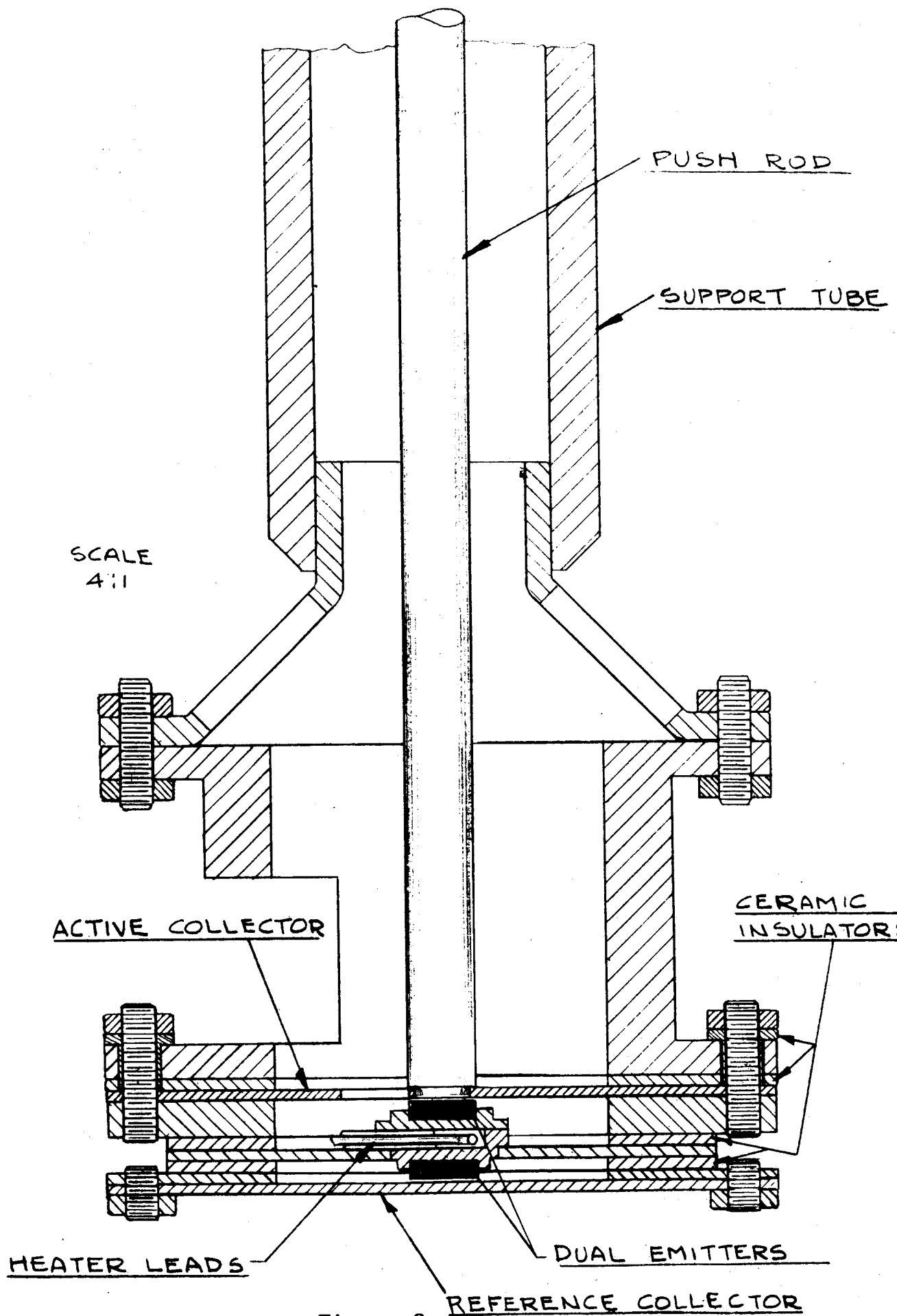
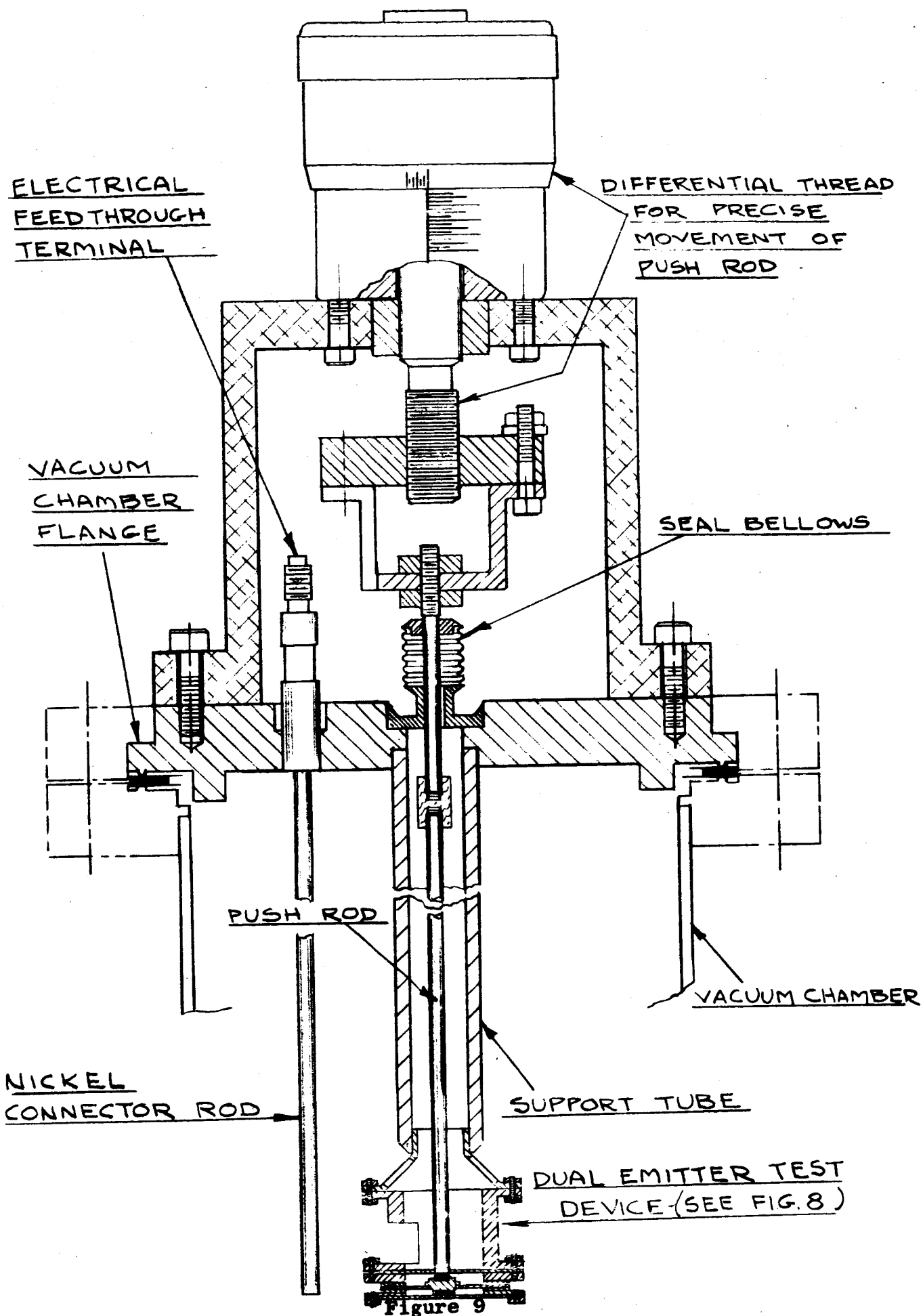
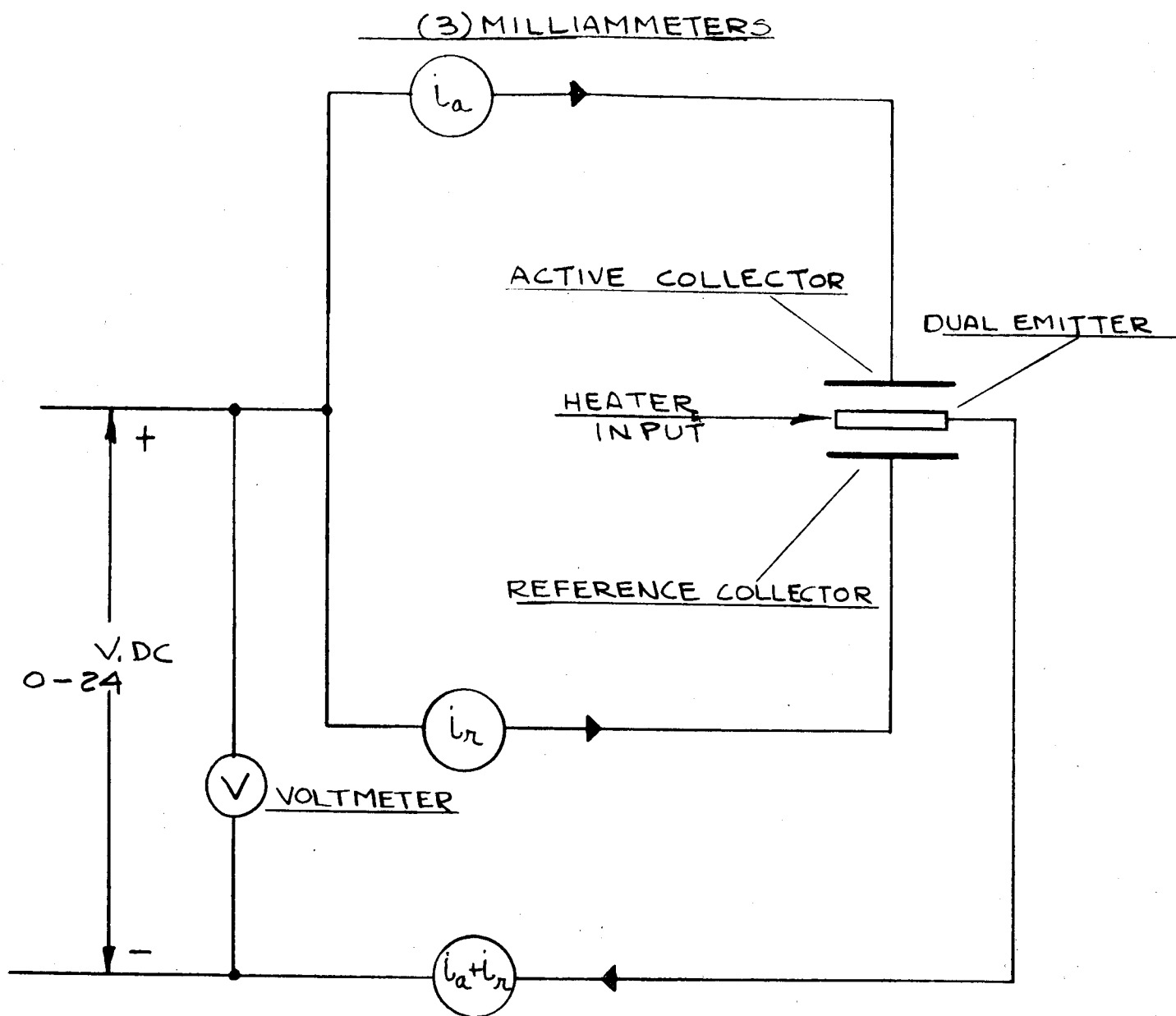


Figure 8

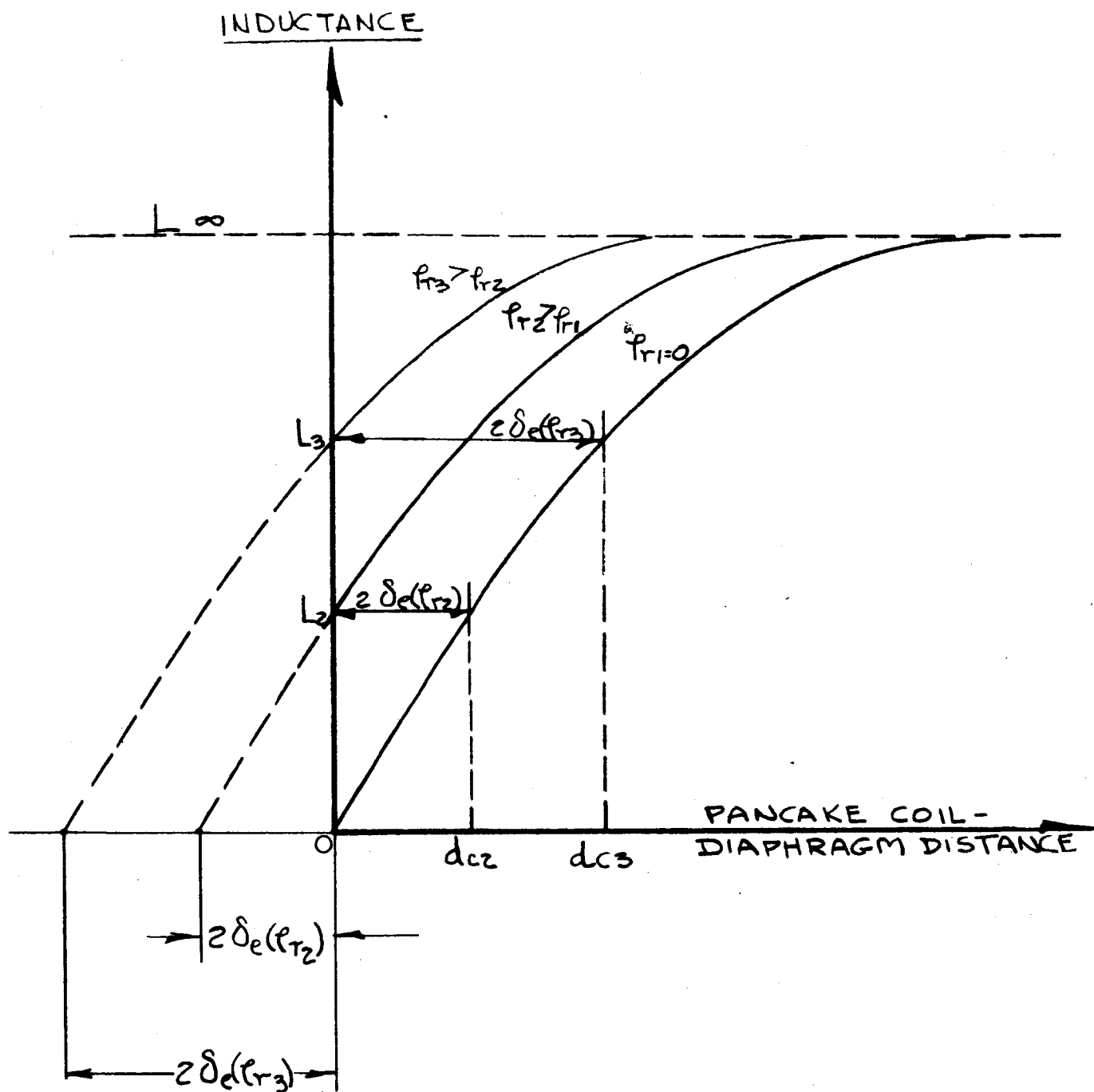
Dual Emitter Test Device



Dual Emitter Test Device - Vacuum Chamber Installation



**Figure 10**  
**Thermionic Test Circuitry**



**Figure 11**  
**Inductance-Distance Characteristics**

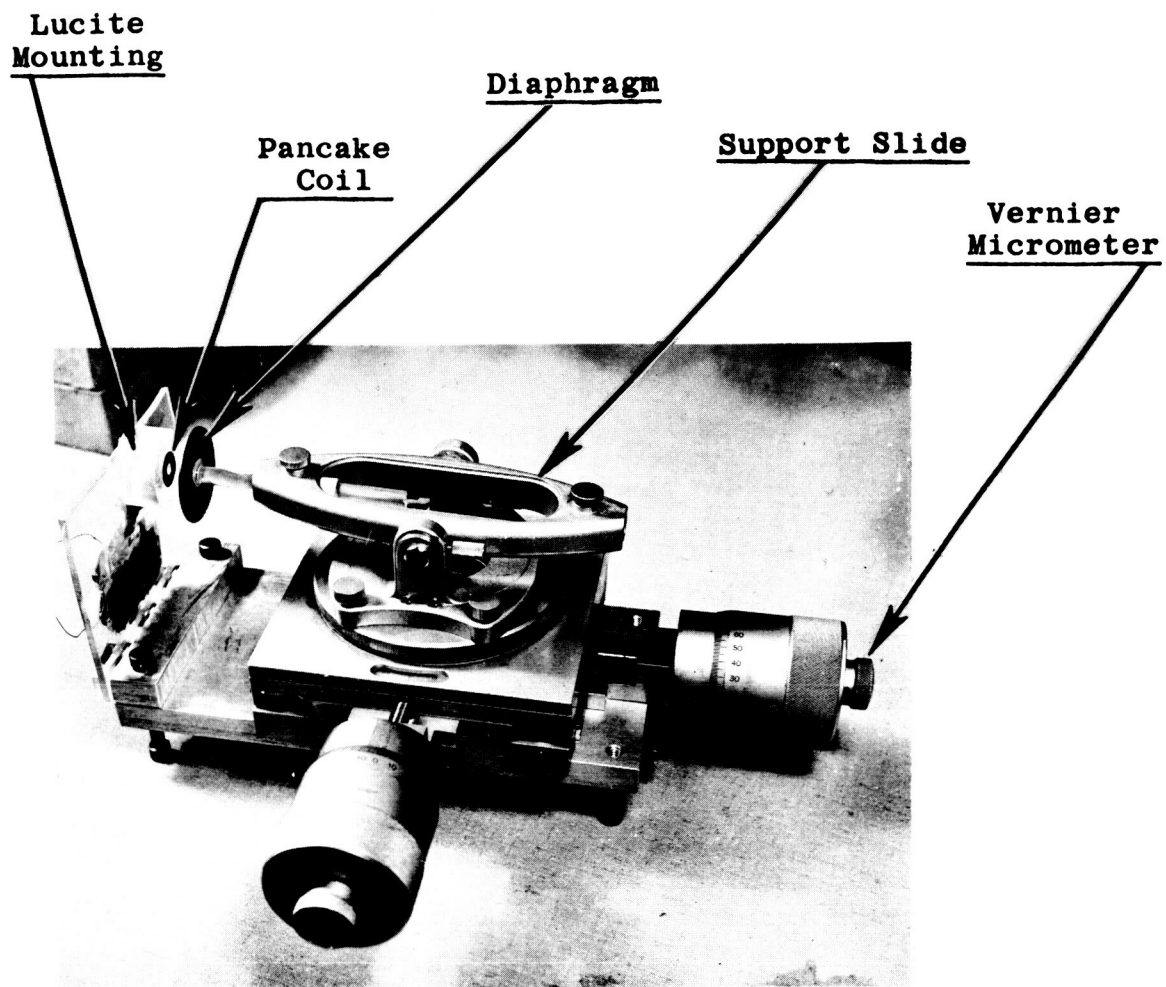


Figure 12  
Variable Impedance Test Fixture

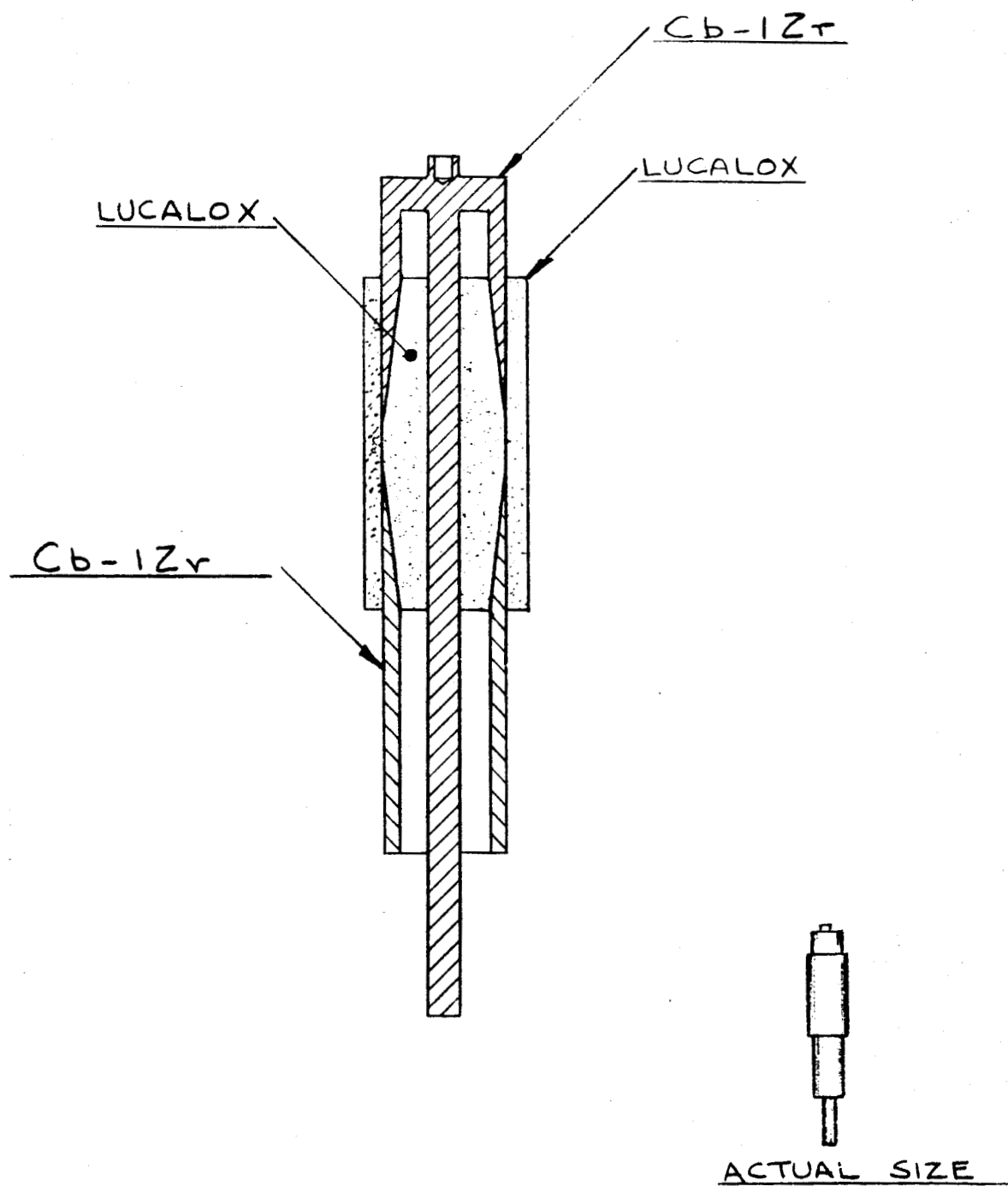


Figure 13  
Electrical Terminal

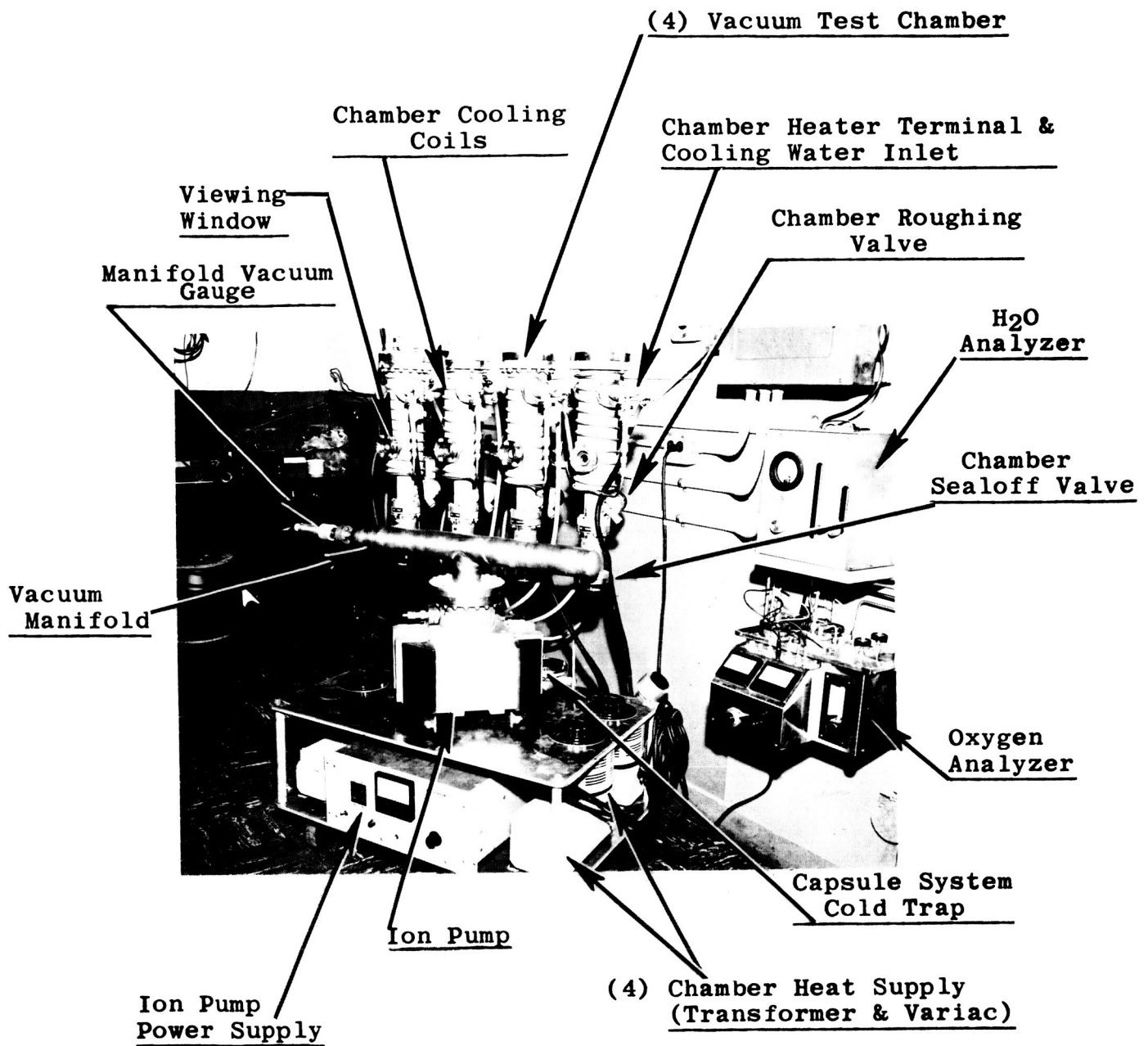


Figure 14  
Test Facility

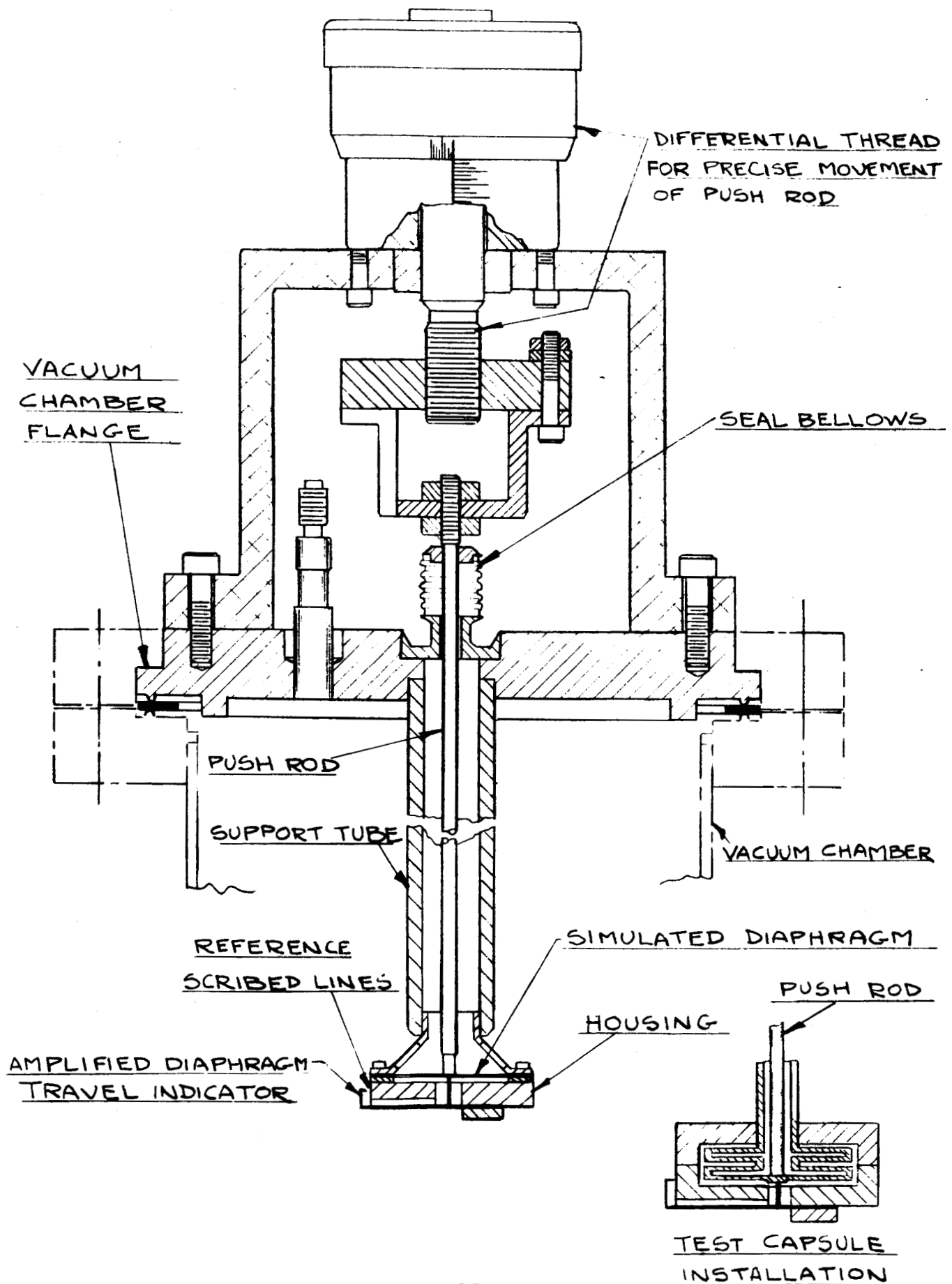


Figure 15

Diaphragm Motion Amplifier System



#### LIST OF REFERENCES

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2. Ibid., p. 167
3. R. E. Engdahl, "First Quarterly Report, Pressure Measuring Systems for Closed Cycle Liquid Metal Facilities", NASA CR-54140, July 2, 1964
4. G. L. Kehl, "Principles of Metallographic Laboratory Practice", Third Edition, McGraw-Hill, 1949, p. 92-93

APPENDIX A  
NOMENCLATURE

a	Radius of individual turn of pancake coil
A	Thermionic constant, 120 amperes/cm <sup>2</sup> (°K) <sup>2</sup>
A <sub>c</sub>	Area of capacitor plate
A <sub>e</sub>	Thermionic emitter area
B	Thermionic constant
C	Capacitance between pancake coil and diaphragm
C <sub>t</sub>	Transmission line capacitance
d	Thermionic emitter-collector distance
d <sub>a</sub>	Thermionic emitter - pressure actuated collector distance
d <sub>c</sub>	Pancake coil - diaphragm distance
d <sub>r</sub>	Thermionic emitter-reference collector distance
e	Electronic charge (1.6 X 10 <sup>-19</sup> coulomb)
E <sub>i</sub>	Input voltage to impedance bridge
E <sub>o</sub>	Output voltage of impedance bridge
f	Frequency
F.D.	Fineness of detail of objective lens
FL <sub>c</sub>	Thermionic collector Fermi level energy

NOMENCLATURE (cont'd)

$FL_e$	Thermionic emitter Fermi level energy
$G_t$	Transmission line conductance
$H_n$	Total axial induction field related to $n^{th}$ turn of pancake coil
$H_o$	Induction field at center of conductor loop
$H_z$	Axial induction field component (cylindrical coordinates)
$H_\rho$	Radial induction field component (cylindrical coordinates)
$i_a$	Thermionic active collector current
$i_o$	Pancake coil loop current
$i_r$	Thermionic reference collector current
$I$	Thermionic current density
$\mathfrak{F}'_1, \mathfrak{F}'_2$	Elliptic integrals related to pancake coil
$\mathfrak{F}''_1, \mathfrak{F}''_2$	Elliptic integrals related to image coil
$I_c$	Current density for critical thermionic emitter
$I_s$	Saturation emission capability of a surface (current density)
$j$	$\sqrt{-1}$
$K$	The Boltzmann Constant ( $1.38 \times 10^{-23}$ joule/deg.K)

NOMENCLATURE (cont'd)

L	Pancake coil inductance
L <sub>t</sub>	Transmission line inductance
m,n	Indexing parameter
n <sub>r</sub>	Index of refraction
N	Number of turns in pancake coil
N.A.	Numerical aperture of objective lens
r <sub>i</sub>	Inner radius of coaxial cable
r <sub>o</sub>	Outer radius of coaxial cable
R <sub>t</sub>	Transmission line resistance
s	Distance along transmission line from the input end
S	Transmission line length
S <sub>b</sub>	Bartberger factor
t	Time
T	Temperature
T <sub>c</sub>	Critical emitter temperature above which space charge occurs
V	Voltage applied to thermionic collector
V <sub>c</sub>	Effective emitter-collector potential difference

NOMENCLATURE (cont'd)

$V_e$	Potential due to thermionic space charge effect
$V_m$	Voltage generated in individual turn of pancake coil
$V_t$	Total voltage generated in pancake coil
$x_c$	Distance from collector to maximum space charge
$x_e$	Distance from emitter to maximum space charge
$X_c$	Pancake coil reactance
$2z_e$	Spacing between pancake and image coils
$Z_i$	Input impedance of transmission line
$Z_L$	Terminating load impedance of transmission line
$Z_o$	Characteristic impedance of transmission line
$\alpha$	Transmission line attenuation constant
$\beta$	Transmission line phase constant
$\gamma$	Transmission line propagation constant
$\delta$	Skin depth in a medium
$\delta_e$	Skin depth at which field becomes negligible

NOMENCLATURE (cont'd)

$\epsilon$	Dielectric constant of medium =
$\epsilon_0$	Dielectric constant of vacuum ( $8.854 \times 10^{-12}$ farad/meter)
$\epsilon_r$	Relative dielectric constant of medium
$\lambda$	Wavelength in medium
$\lambda_i$	Wavelength of illuminating light
$\lambda_0$	Wavelength in vacuum
$\mu$	Permeability of medium =
$\mu_0$	Permeability of vacuum ( $1.257 \times 10^{-6}$ henry/meter)
$\mu_r$	Relative permeability of medium
$\mu_s$	Half-angle subtended by objective lens
$\pi$	3.1416
$\rho_r$	Resistivity of material
$\sigma$	Conductivity of material
$\phi$	Thermionic work factor
$\phi_c$	Thermionic collector work function
$\phi_e$	Thermionic emitter work function
$\phi_m$	Flux linked by individual turn of pancake coil

NOMENCLATURE (cont'd)

$\omega$	Angular frequency - $2\pi f$
$(x, y, z)$	Cartesian coordinates
$(\rho, \phi, z)$	Cylindrical coordinates
$(r, \theta, \phi)$	Spherical coordinates

## APPENDIX B

### CALCULATION OF PANCAKE COIL INDUCTANCE

Using the analysis presented in the First Quarterly Report, an effort was made to determine, by slide rule calculations, the inductance of a single turn pancake coil in the presence of a conducting diaphragm. The inductance may be expressed as

$$L = \pi \mu_0 a^2 \int_0^a [F_c - F_i] \rho d\rho \quad (B-1)$$

where  $\mu_0$  is the permeability of vacuum;  $a$  is the radius of the current loop;  $F_c$  and  $F_i$  are functions involving elliptic integrals and dependent upon the parameter  $a$  and the cylindrical coordinates  $z$  and  $\rho$ . The subscripts (c) and (i) refer to pancake coil and image coil parameters respectively. The distance between the pancake and image coils is related to the diaphragm spacing and appears in  $F_i$ .

The initial effort involved the use of a spacing of 0.006 inch which decreases to 0.004 inch under pressure. The loop radius was assumed to be  $a = 0.4$  inch. Calculations showed that for this spacing, the difference between the  $F_c$  and  $F_i$  terms was too small to be evaluated by slide rule and a result was not obtainable.



To remedy the situation, the diaphragm spacing was increased to 0.100 inch and a travel of 0.008 inch under pressure was postulated. Using these parameters, an estimate of L was obtained for a spacing of 0.100 inch. Using a number of values of  $\rho$ , it was found that  $(F_c - F_i)$  is of a tangent form, changing from zero at  $\rho = 0$  to infinity at  $\rho = 0.4$ . The analytical treatment of the integral involved the adoption of a tangent function in place of  $(F_c - F_i)$ . It appeared that a reasonable form would be

$$(F_c - F_i) \cong 3 \tan (90\rho/0.4) \text{ degrees} \quad (\text{B-2})$$

Using this approach and integrating to  $\rho = 0.395$  inch (to avoid the complication of obtaining infinity at  $\rho = 0.4$ ) a value of  $L = 0.2$  microhenry was obtained. If the coefficient of the tangent function is raised to 4 and the integration carried out to  $\rho = 0.399$  inch, the value of L becomes 0.5 microhenry. These changes are within reason. Therefore, a range of L would be 0.2 - 0.5 microhenry.

From this point, an effort was made to evaluate the inductance change obtained when the diaphragm

has moved 0.008 inch to a spacing of 0.092 inch. In doing this, it was found that the parameter  $(F_C - F_i)$  could be approximated by the same tangent function as before. It must be stressed that this evaluation was obtained by use of a limited number of  $\rho$  values and the tangent representation fits equally as well for diaphragm spacings of 0.100 and 0.092 inch. This means that, as far as slide rule calculations can determine, there is no inductance change with diaphragm spacing.

Checking the values of  $F_C - F_i$  for spacings of 0.100 and 0.092 at given values of  $\rho$  results in differences starting at about 10 percent for small  $\rho$  values and decreasing to about 1 percent as  $\rho$  approaches 0.4. Since the value of the integration will depend primarily on large  $\rho$  values, the inductance will change by much less than 10 percent. The exact percentage change cannot be determined manually. The integration must be performed on the actual values of  $(F_C - F_i)$ . This means that

many values of  $\rho$  must be used and a geometrical determination of the area under the curve must be made. This is most easily and most accurately obtained by computer operations.

In addition to the above statements, it must be remembered that this involved only one current loop. The proposed pancake coil may have as many as 20 turns. Therefore, this calculation must be done 20 times and the results summed up.

It, therefore, appears that the developed impedance analysis can be practically solved only by a computer technique.

## APPENDIX C

### FINENESS OF DETAIL OF AN OBJECTIVE LENS

According to Kehl (Reference 4), the fineness of detail, or the ability of an objective lens to produce sharply defined separate images of closely spaced detail in the object, is dependent upon the numerical aperture of the objective and the wavelength of light used to illuminate the object. If the aperture of the objective is completely flooded with light, the fineness of detail obtained with the particular objective will be a maximum, and may be expressed as

$$\text{F.D.} = \frac{\lambda_i}{2(\text{N.A.})} \quad (\text{C-1})$$

where  $\lambda_i$  is the wavelength of the illuminating light and N.A. is the numerical aperture of the objective.

The numerical aperture may be expressed as

$$\text{N.A.} = n_r \sin \mu_s \quad (\text{C-2})$$

where  $n_r$  is the index of refraction of the medium between the lens and the object and  $\mu_s$  is one-half the angle subtended by the lens.

If  $\mu_s = 30^\circ$ , N.A. becomes 0.5 in air ( $n_r = 1$ ). For the binocular microscope at 4 inch working distance, N.A. becomes 0.058. For green light illumination ( $\lambda_i = 0.00053$  millimeter), the fineness of detail is  $0.00053/2(0.058)$  mm. or 180 microinches.

This result assumes ideal conditions. In the binocular microscope, only one-half of the objective lens is used and the center of the lens is obscured by a mirror. Also the light is not passing through the objective normally, but at a slight angle. Thus a closer approximation would be

$$\text{F.D.} = \frac{\lambda_i}{\text{N.A.}} \quad (\text{C-3})$$

resulting in 360 microinches resolution.

Even if a relay microscope at 4 inch working distance were used, the relay telescope would have an N.A. of approximately 0.1 and the microscope would have an N.A. of 0.66. The overall N.A. of the system would be limited to the smallest N.A. of the parts of the system, i.e. N.A. = 0.1.

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